CLAIMS

What is claimed is:

- 1 1. A method comprising:
- determining a location of one or more regions on a reticle that come in contact
- 3 with a reticle handling or support surface; and
- 4 generating a pattern to be written on the reticle, the pattern including one or
- 5 more cut-out regions corresponding to the one or more regions that have been
- 6 determined to come in contact with the reticle handling or support surface.
- 1 2. The method of claim 1, wherein determining a location of the one or more
- 2 regions comprises determining a type of support surface used for the reticle.
- 1 3. The method of claim 1, wherein determining a location of the one or more
- 2 regions comprises determining a type of carrier used for the reticle.
- 1 4. The method of claim 1, wherein determining a location of the one or more
- 2 regions comprises determining a type of handling apparatus used for the reticle.
- 1 5. The method of claim 1, wherein determining a location of the one or more
- 2 regions comprises determining a type of storage apparatus used for the reticle.
- 1 6. The method of claim 1, wherein determining a location of the one or more
- 2 regions comprises determining a manufacturing process used with the reticle.

- 1 7. The method of claim 6, wherein determining a location of the one or more
- 2 regions comprises determining one or more required features to be written on the
- 3 reticle.
- 1 8. The method of claim 1, further comprising determining a size of each cut-out
- 2 region.
- 1 9. The method of claim 1, further comprising writing the pattern on a reticle blank.
- 1 10. The method of claim 9, further comprising developing and etching the pattern
- 2 to remove reticle surface chrome from the regions that have been determined to
- 3 come in contact with the reticle handling or support surface.
- 1 11. A reticle comprising:
- 2 a circuit pattern to be exposed on a wafer; and
- 3 one or more chrome cut-out regions positioned where a reticle handling or
- 4 support apparatus has been determined to come in contact with the reticle.
- 1 12. The reticle of claim 11, further comprising a barcode.
- 1 13. The reticle of claim 11, further comprising an alignment feature.
- 1 14. The reticle of claim 11, further comprising a pellicle to shield the reticle from
- 2 particles.
- 1 15. The reticle of claim 11, further comprising a reticle manufacturing structure.

- 1 16. A method comprising:
- writing a pattern on a blank reticle having a layer of photoresist and a layer of
- 3 chrome, the pattern including one or more cut-out regions that have been
- 4 determined to come in contact with a reticle handling or support apparatus;
- 5 developing the pattern to remove the photoresist layer and reveal the chrome
- 6 layer in the regions determined to come in contact with the reticle handling or
- 7 support apparatus; and
- 8 etching away the chrome layer to remove chrome from the regions
- 9 determined to come in contact with the reticle handling or support apparatus.
- 1 17. The method of claim 16, wherein the layer of photoresist is positive and
- 2 developing the pattern comprises exposing and removing the photoresist layer from
- 3 the written regions to reveal the chrome layer.
- 1 18. The method of claim 17, wherein etching away the chrome layer comprises
- 2 etching away the chrome layer from the written regions to reveal a glass layer of the
- 3 reticle.
- 1 19. The method of claim 16, wherein the layer of photoresist is negative and
- 2 developing the pattern comprises exposing and removing the photoresist layer from
- 3 the unwritten regions to reveal the chrome layer.
- 1 20. The method of claim 19, wherein etching away the chrome layer comprises
- 2 etching away the chrome layer from the unwritten regions to reveal a glass layer of
- 3 the reticle.

- 1 21. The method of claim 16, wherein writing a pattern on a blank reticle comprises
- 2 writing a pattern on a blank reticle via an E-beam machine.
- 1 22. The method of claim 16, wherein writing a pattern on a blank reticle comprises
- 2 writing a pattern on a blank reticle via a laser writer.